

Fig. 1

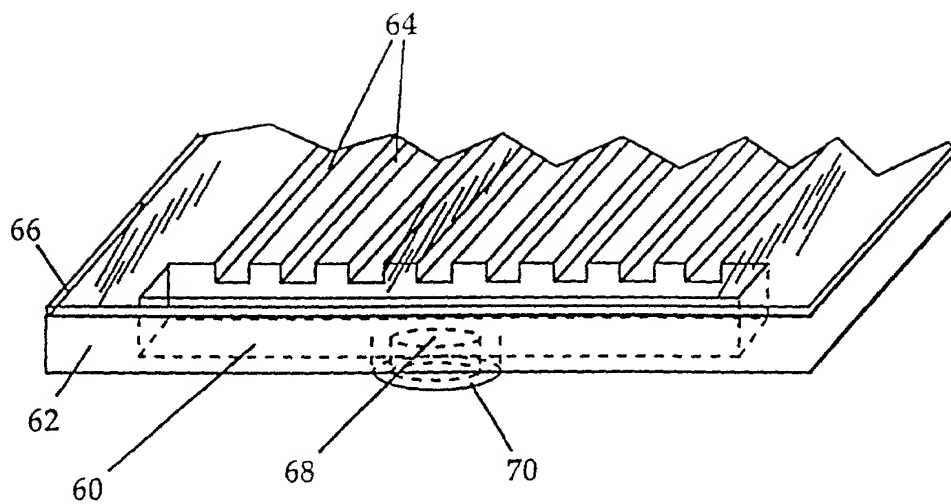


Fig. 2

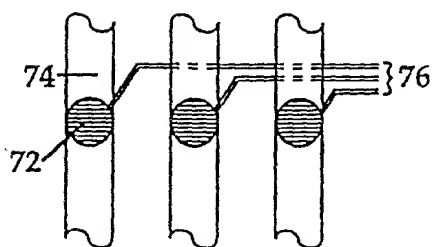


Fig. 3A

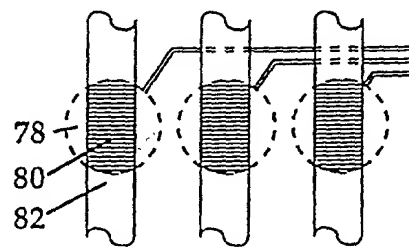


Fig. 3B

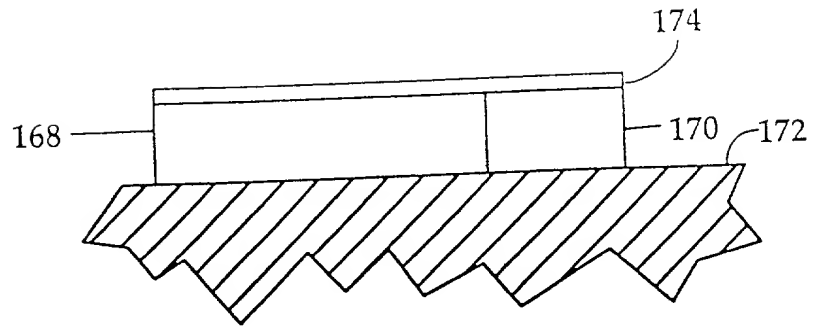


Fig. 4A

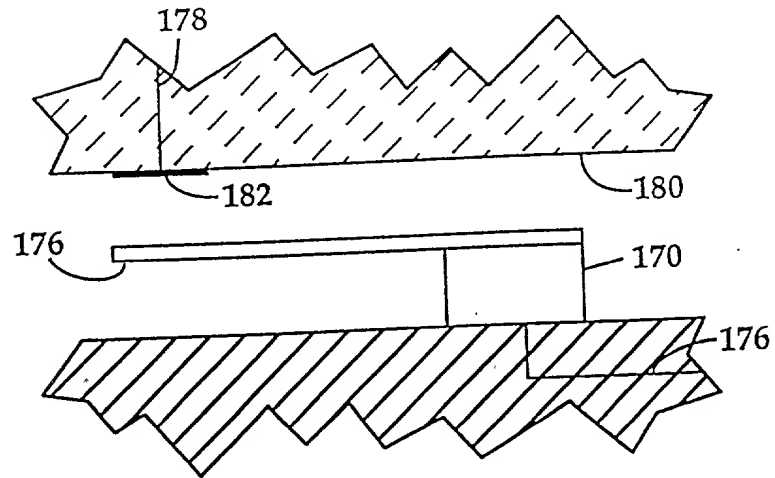


Fig. 4B

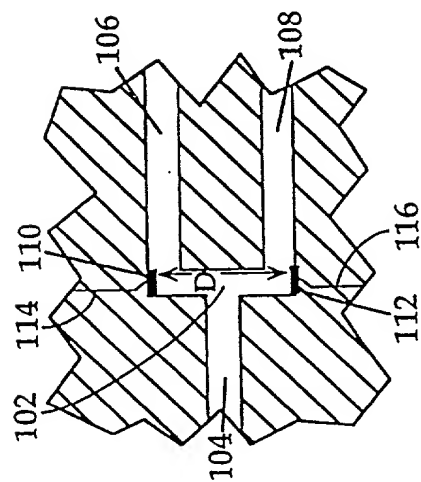


Fig. 5A

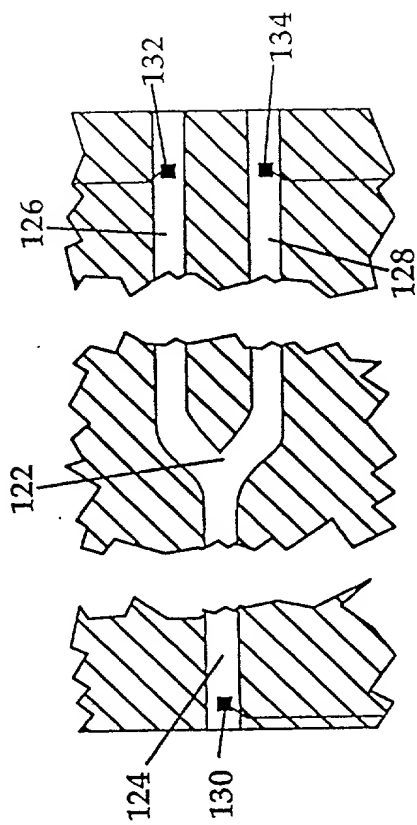


Fig. 5B

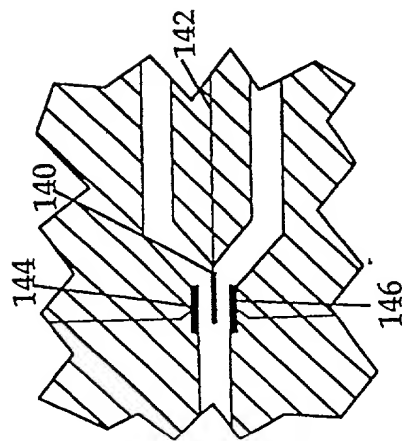


Fig. 5C

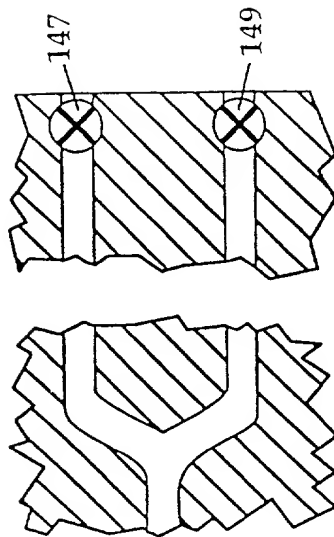


Fig. 5D

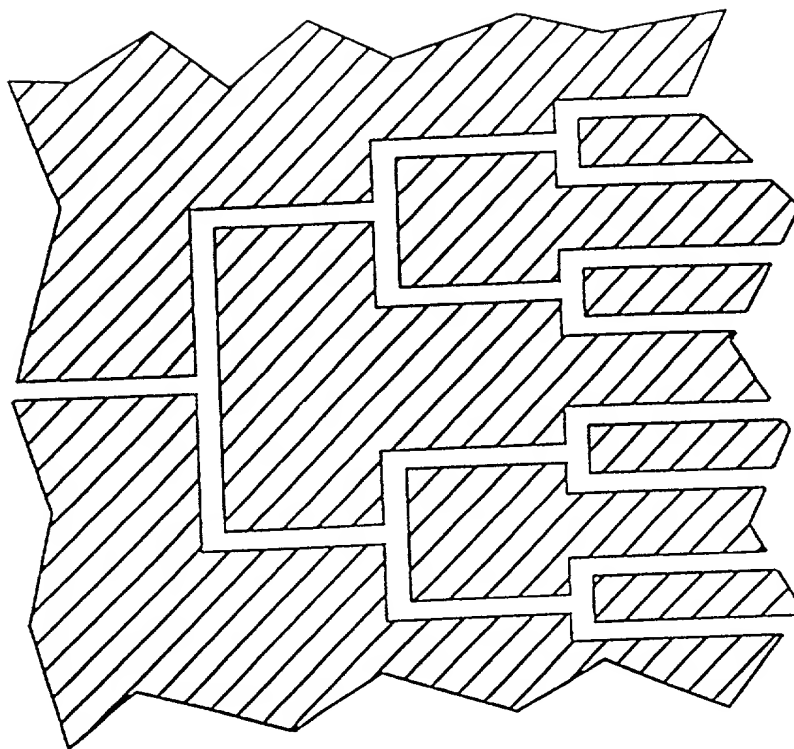


Fig. 6

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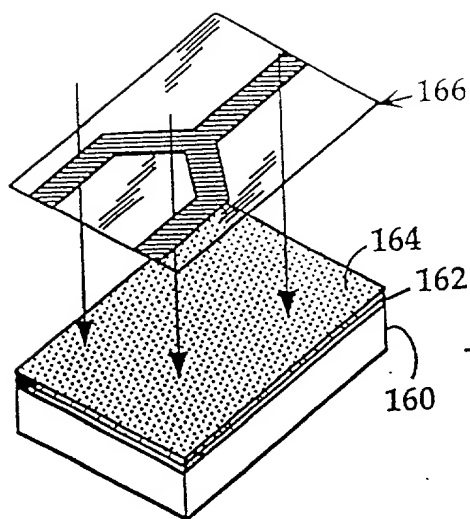


Fig. 7A

develop
and rinse

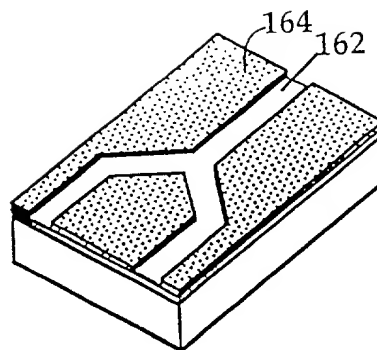


Fig. 7B

1. etch SiO_2
2. remove resist

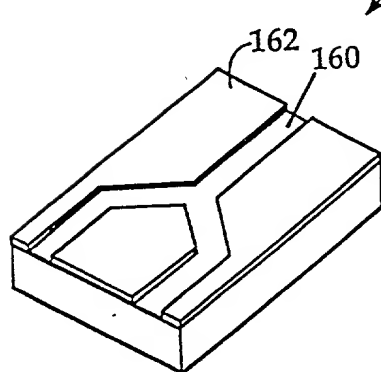


Fig. 7C

etch Si

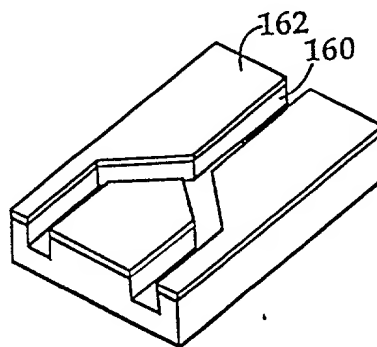


Fig. 7D

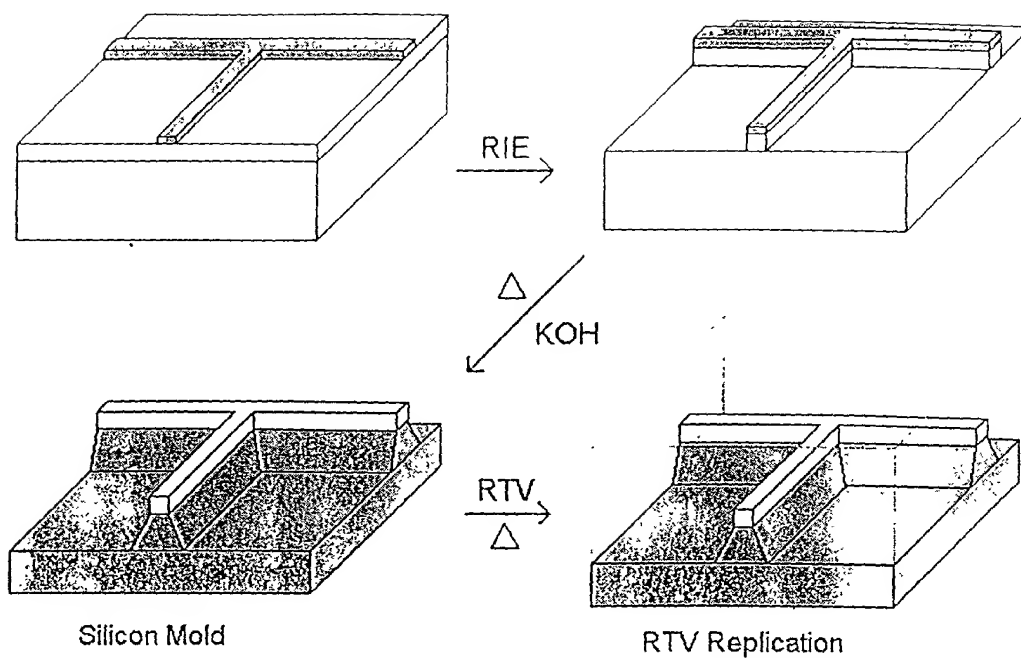


Fig. 8

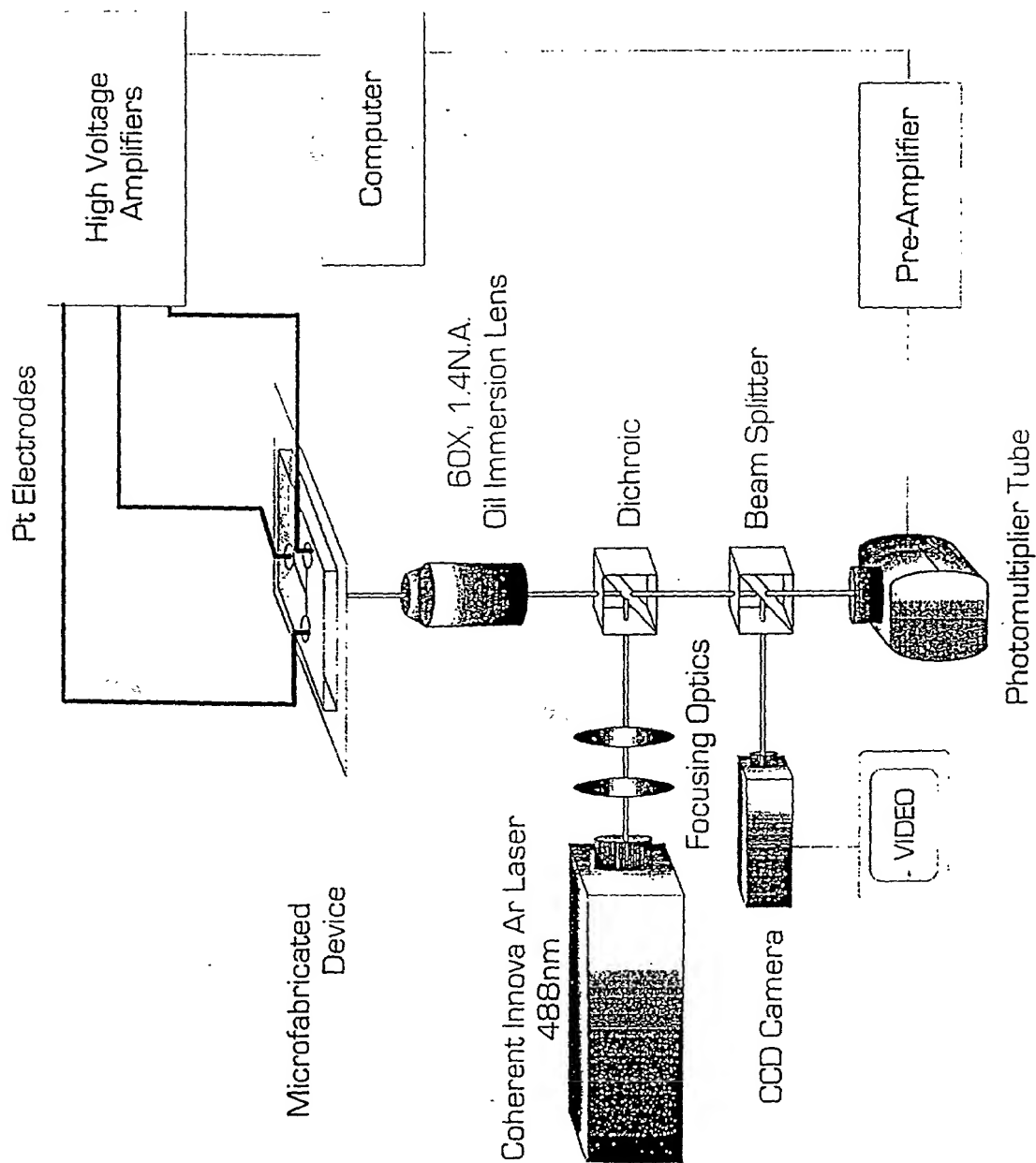


Fig 9



Fig 10

Fig. 11

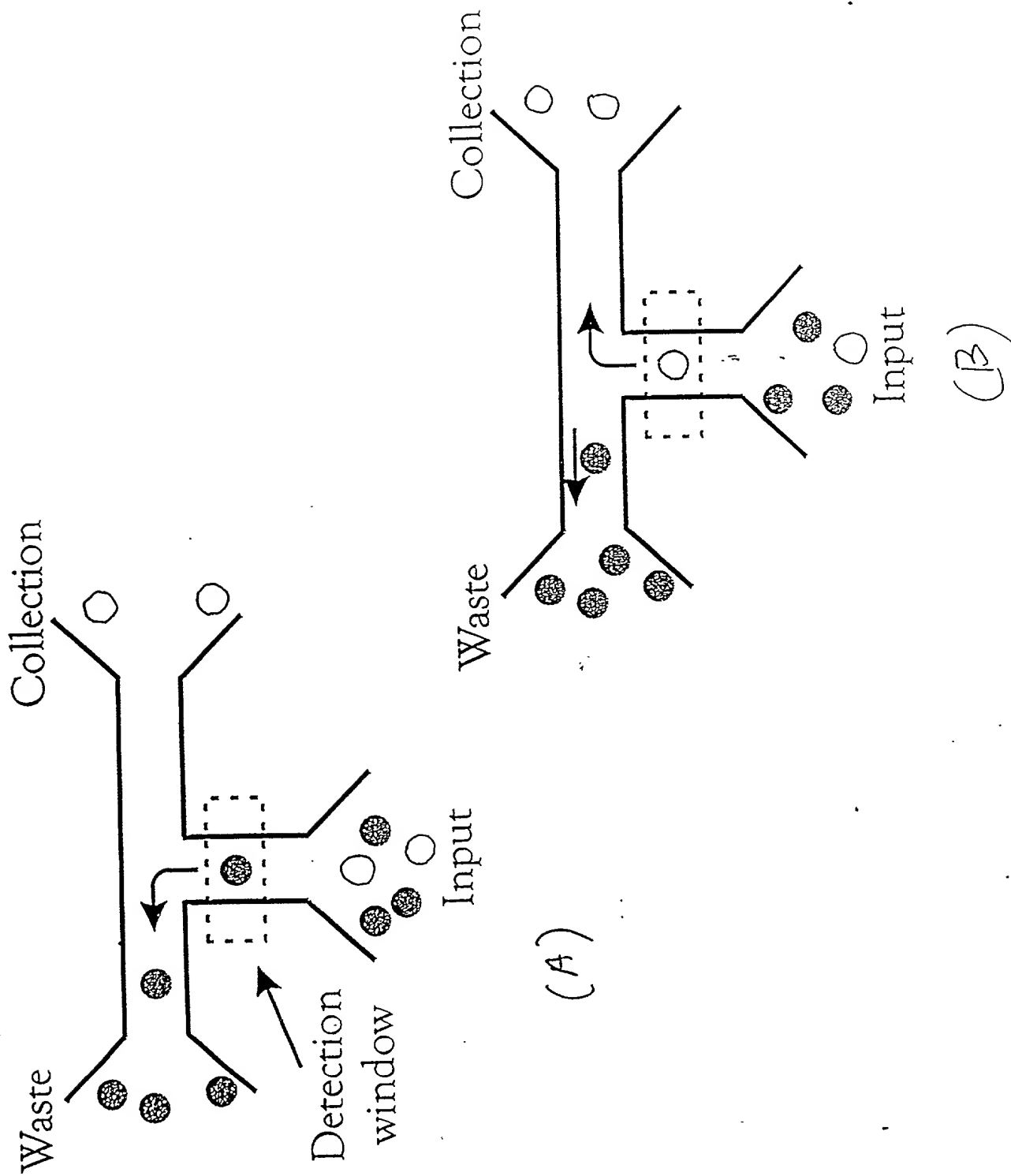
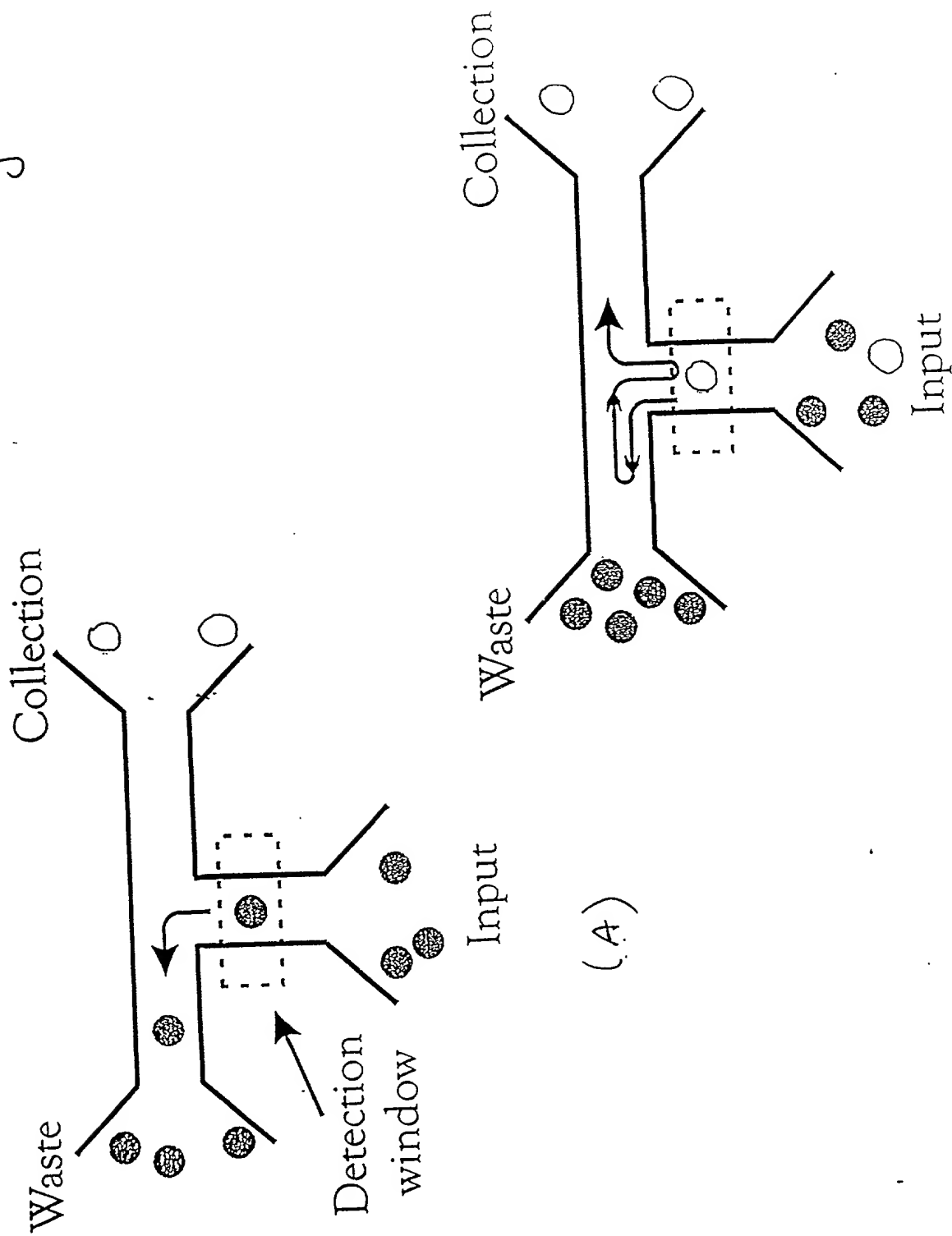


Fig 12



(A)

(B)

T7 DNA/ T7 Primer

3.45mW laser power/ 2.450kV APD bias

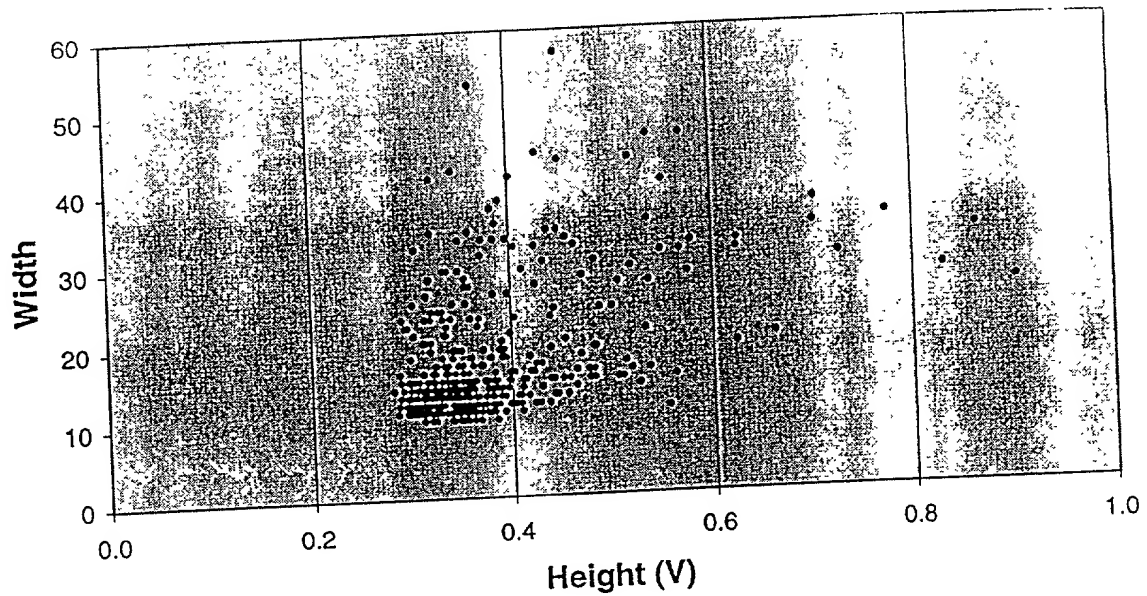


FIG. 13

λ DNA/ T7 Primer

3.35mW laser power/ 2.450kV APD bias

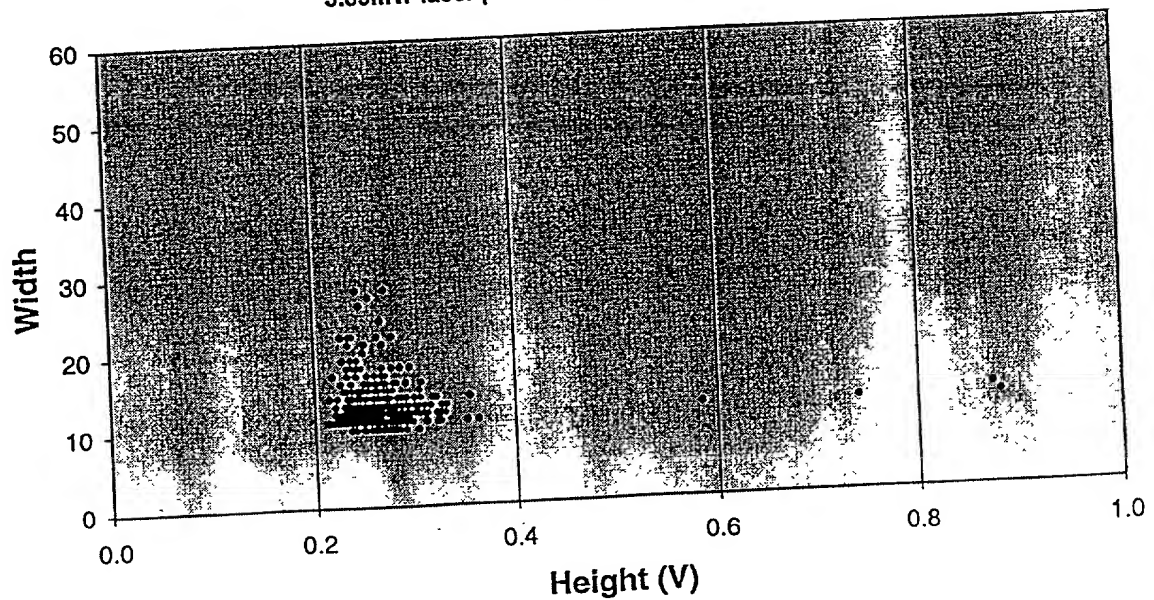
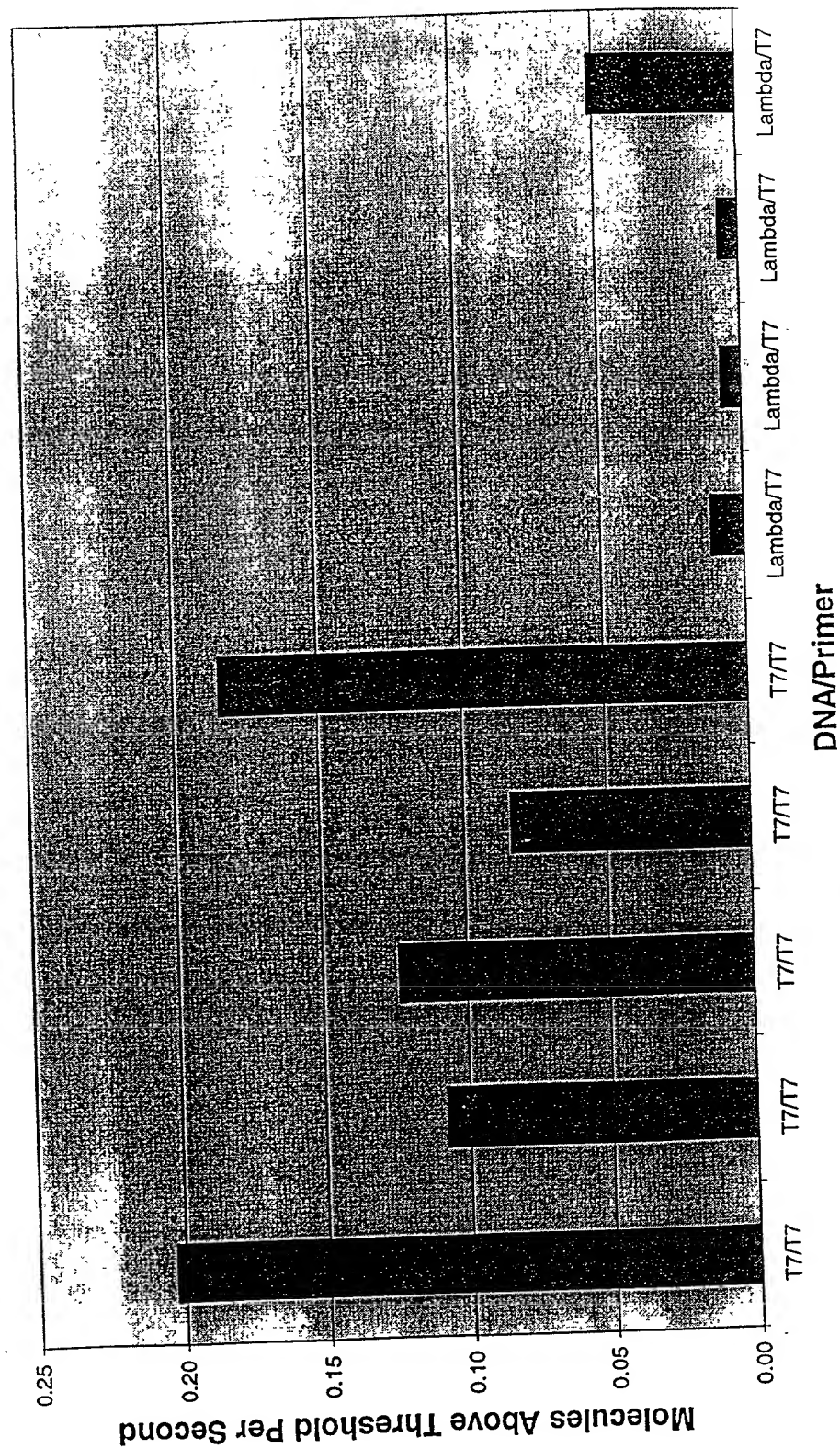


FIG. 14

Molecular Diagnostics



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CALTECH